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jc914 U.S. PTO

02-14-02 A

Docket No. 5018/ISM/CORE MCVD

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application  
Commissioner of Patents and Trademarks  
Washington, D.C. 20231

102 U.S. PRO  
02/11/02

Re: Inventor(s): Avi TEPMAN and Lawrence Chung-lai LEI  
Title: VARIABLE FLOW DEPOSITION APPARATUS AND METHOD IN SEMICONDUCTOR SUBSTRATE PROCESSING

Transmitted herewith is the patent application identified above, including:

- Specification, claims and abstract, totaling 29 pages.  
 Drawings totaling 4 pages,    Formal    Informal.  
 Executed Declaration and Power of Attorney.  
 Assignment of the invention to **Applied Materials, Inc.**  
 Assignment Recordation Cover Sheet  
 Information Disclosure Statement (37 CFR 1.98)

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	51	-20=	31	X\$18.00	\$ 558.00
Independent Claims	6	-3=	3	X\$84.00	\$ 252.00
Basic Filing Fee				\$740.00	\$ 740.00
<b>TOTAL FEES</b>					<b>\$1550.00</b>

- The Commissioner is hereby authorized to charge \$1550.00 to Deposit Account No. 50-1074.
- The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.

Please address all future correspondence to:

PATENT COUNSEL  
APPLIED MATERIALS, INC.  
Legal Affairs Department  
P.O. BOX 450A  
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231.

Express Mail Receipt No. EY049834328US

Date of Deposit 2-11-02

Signature Robert W. Mulcahy

Respectfully submitted,

Robert W. Mulcahy  
Registration No. 25,436